

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:	)	
	)	Examiner:
Yuichiro Nakamura et al.	)	
	)	Group Art Unit:
Application No.:	)	
	)	
Corresponding International Filing No.:	)	
<b>PCT/JP2005/002209</b>	)	
	)	
Filed: Herewith	)	
	)	
For: SPUTTERING TARGET WITH	)	
FEW SURFACE DEFECTS, AND	)	
SURFACE PROCESSING	)	
METHOD THEREOF	)	

Mail Stop PCT  
 Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

**VERIFICATION OF TRANSLATION**

Sir:

I, Isamu Ogoshi, having been warned that willful false statements and the like are punishable by fine or imprisonment or both, under section 1001 of Title 18 of the United States Code, and may jeopardize the validity of the above-captioned application and any patent issuing thereon, declare:

(1) I am a patent attorney authorized to practice law in Japan and am engaged in the practice of law with OGOSHI International Patent Office at Toranomon 9 Mori Bldg. 3F, 2-2, Atago 1-Chome, Minato-ku, Tokyo 105-0002, Japan.

(2) I am fluent in the Japanese and English Languages.

(3) I have reviewed the attached translation, and certify that it is an accurate English translation of the Japanese language international application of Yuichiro Nakamura and Akira Hisano filed on February 15, 2005 and given International Application No. PCT/JP2005/002209.

(4) All of the statements made herein of my own knowledge are true and all statements made herein on information and belief are believed to be true.

August 30, 2006

Date

Isamu Ogoshi

Isamu Ogoshi